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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Joseph M. Steigerwald
Serial No.: 10/722,801
Filed: November 26, 2003
For: Electrochemically Polishing Conductive
Films on Semiconductor Wafers

§
§ Art Unit: 2815
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§ Examiner: Sheila V. Clark
§
§
§ Atty Docket: ITL.0947US
§ P15971
§

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 0

Sir:

In response to the office action mailed November 4, 2004, please amend the above-referenced patent application as follows:

Date of Deposit: January 25, 2005

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden
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